

AST-200

Advanced Detection and Metrology System

- Defect Detection & Classification
- Precision Dimensional Metrology
- Automatic and Manual Operation
- Up to 300mm Wafer/Part Capacity

This top performance system is designed for applications where high-speed defect detection and precision measurements on wafers and other parts are required. It is well suited for use as a dedicated production tool or as a versatile process development system. It features a powerful set of automated as well as semi-automatic optical/video tools optimized for high accuracy, production throughput, and ease of use.

This automated and versatile platform can be configured with specialized optical paths across the spectrum utilizing precise part staging. The system offers significant and unique advantages for dual production/engineering use, and provides the perfect solution when both defect detection and dimensional metrology are required.

The system can be configured or customized to meet your exact requirements with a variety of optical and illumination accessories, custom wafer/part fixtures, as well as custom operator interface, data formats and reports.



APPLICATIONS

- Wafer level defect detection & measurement
- Precision MEMS and HD component inspection
- Advanced microelectronics package inspection

POWERFUL

- Designed for automatic/semi-automatic operation
- Extensive defect detection features & capability
- Integrated dimensional metrology features

PRECISE

- Sub-micron precision optical measurements
- High accuracy staging with 0.02 μm linear encoder resolution

FAST

- 50-100 defects/measurements per second typical per field of view
- 200mm/second part staging speed
- [Option] 300mm/second part staging speed

USER FRIENDLY

- Very easy to use, program and set up
- Highly visual data with rich color graphics & video

FLEXIBLE

- Specialized optics and other advanced options
- Optional wafer and other part types handling
- Customizable for application specific solutions

